
Time-Dependent Dielectric Breakdown in High-Voltage GaN MIS-HEMTs: The Role of Temperature

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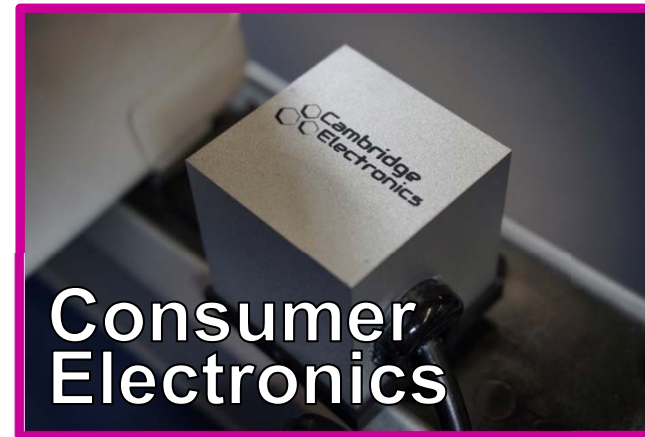
Massachusetts Institute of Technology

Purpose

- Understand time-dependent dielectric breakdown (TDDB) in GaN MIS-HEMTs
- Explore progressive breakdown (PBD) as a means of better understanding physics of gate dielectric degradation

Motivation

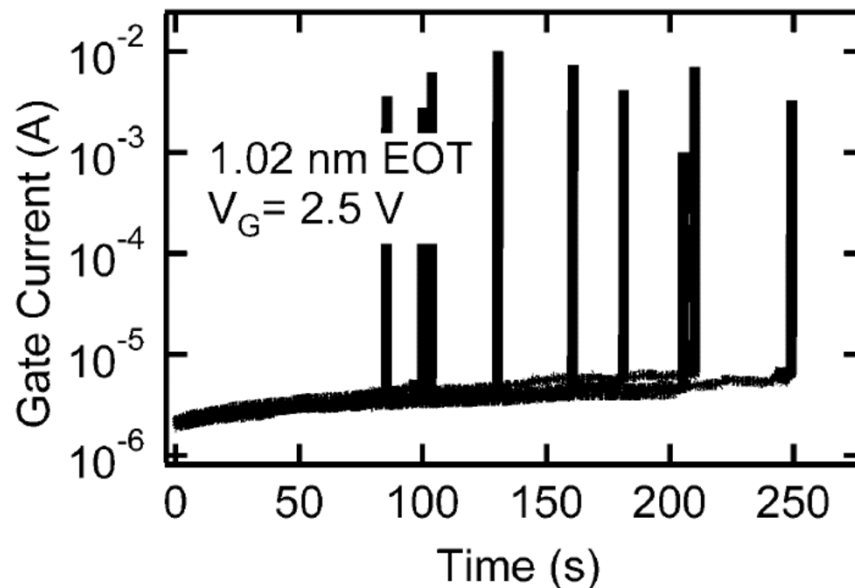
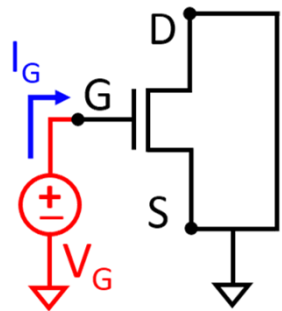
GaN Field-Effect Transistors (FETs) promising for high-voltage power applications → more efficient & smaller footprint



Time-Dependent Dielectric Breakdown

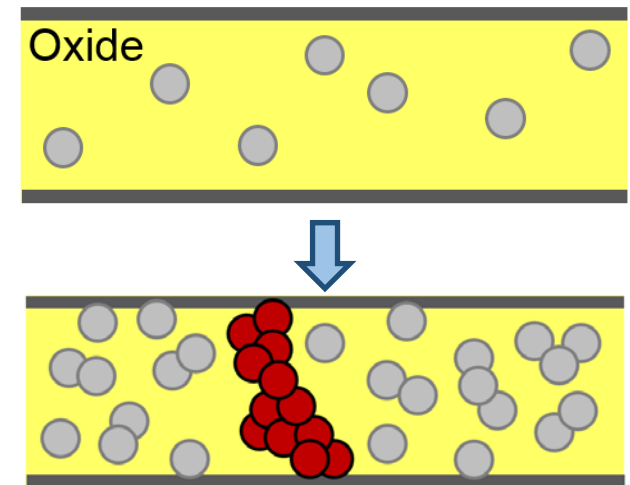
- High gate bias \rightarrow defect generation \rightarrow catastrophic oxide breakdown
- Often dictates lifetime of chip

Typical TDDB experiments:
Si high-k MOSFETs



T. Kauerauf, EDL 2005

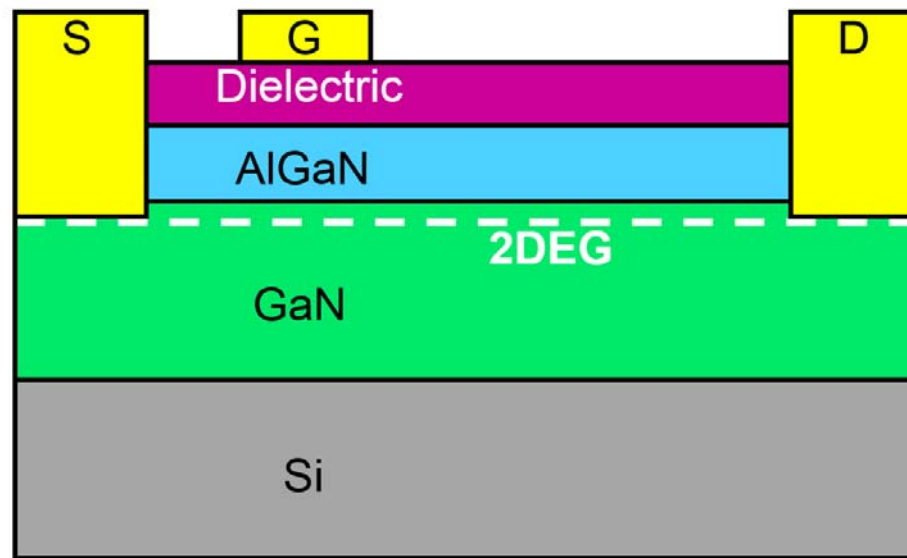
Modeling defect formation



R. Degraeve, MR 2009

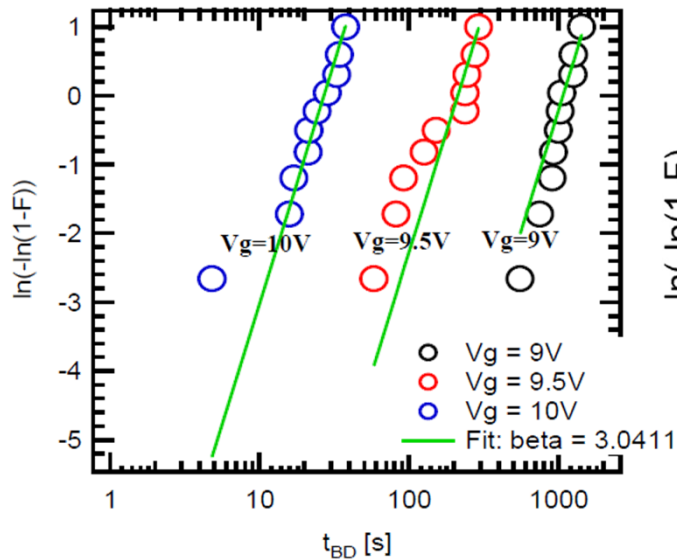
Dielectric Reliability in GaN FETs

AlGaN/GaN metal-insulator-semiconductor high electron mobility transistors (MIS-HEMTs)

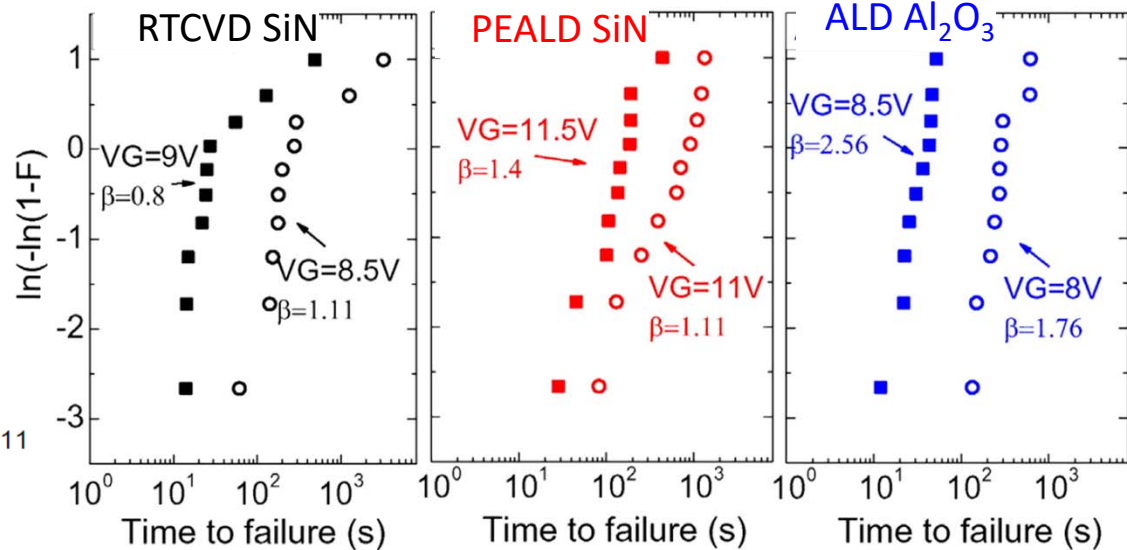


- Goals of this work:
 - What does TDDDB look like in GaN MIS-HEMTs?
 - What is the temperature dependence of TDDDB and what does it tell us about breakdown physics?

TDDDB in GaN MIS-HEMTs



T.-L. Wu, IRPS 2013



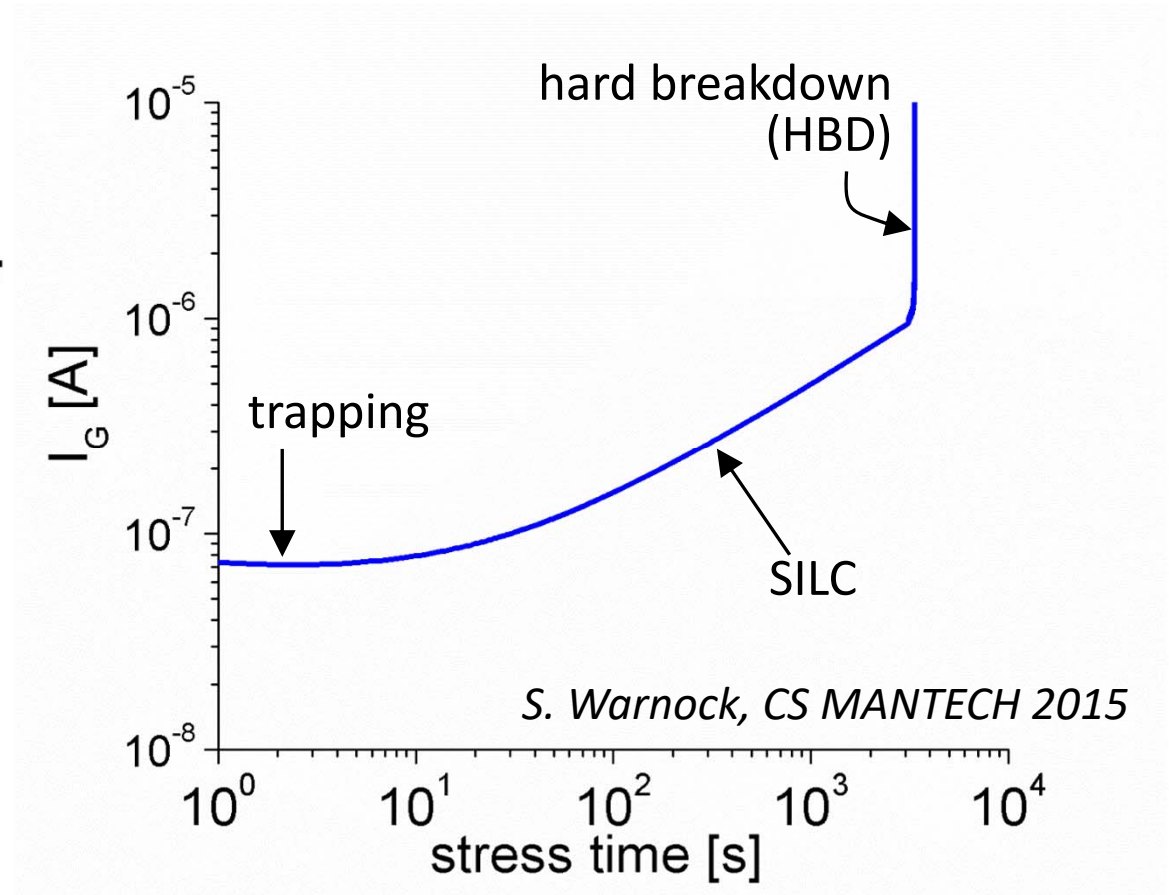
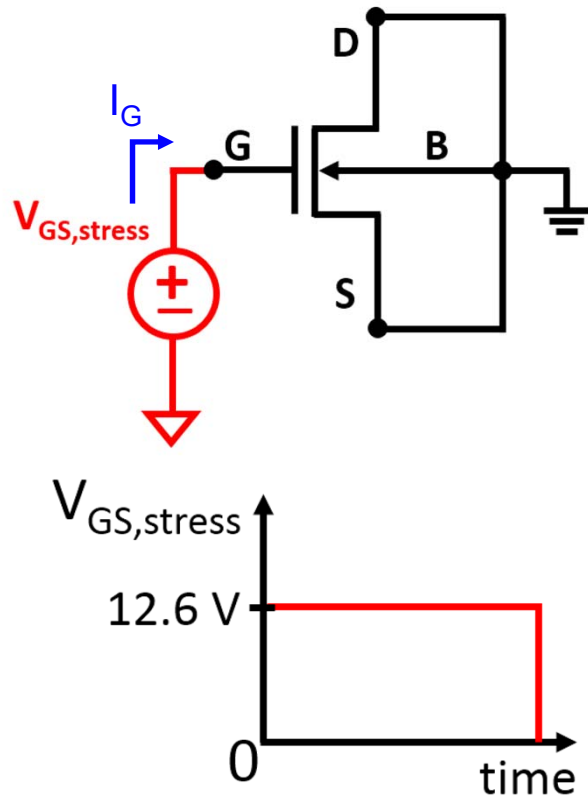
G. Meneghesso, MR 2015

- Classic TDDDB observed
- Studies to date focus largely on: breakdown statistics, lifetime extrapolation, evaluating different dielectrics
- **Goal of this work: temperature dependence of TDDDB**

Experimental Methodology & Breakdown Statistics

Classic TDDB Experiment

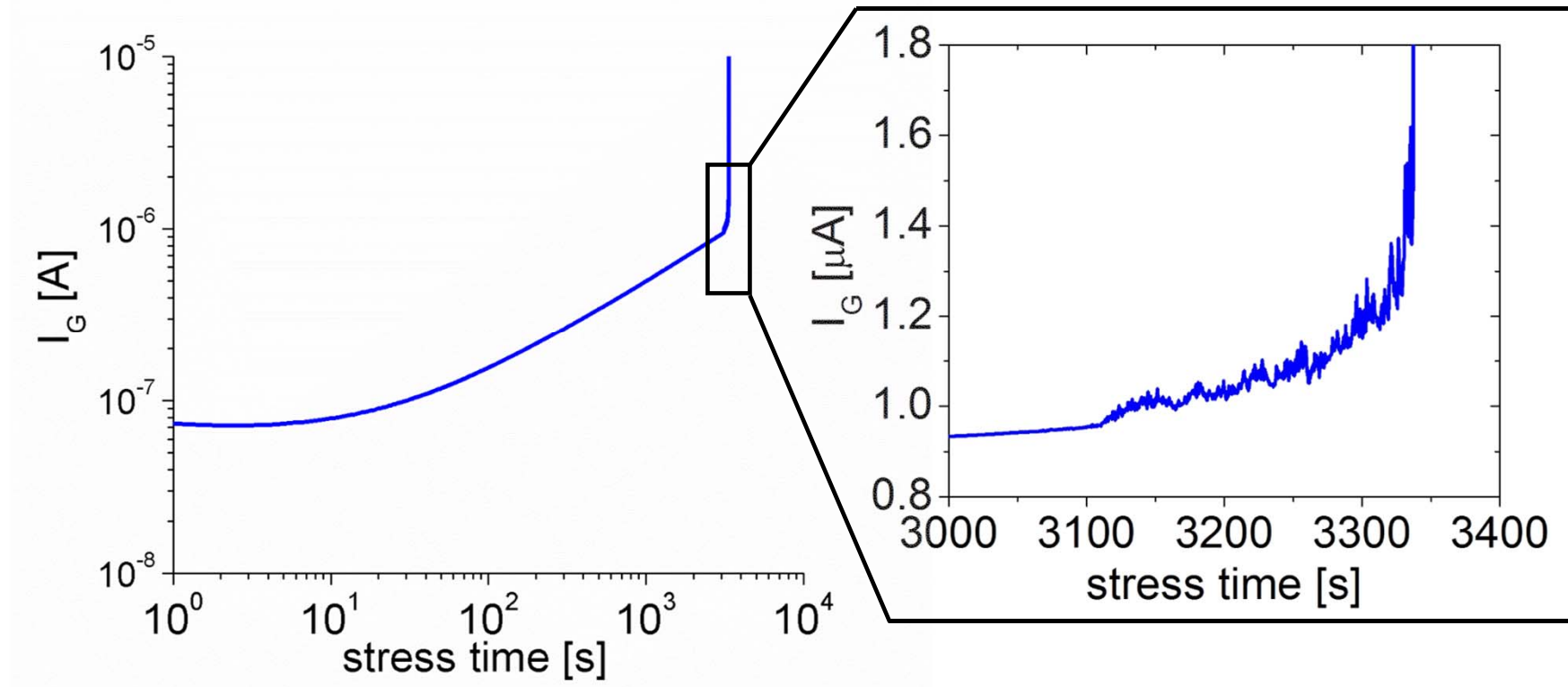
Constant gate-voltage stress:



Experiment gives time to breakdown and shows generation of *stress-induced leakage current* (SILC)

Observing Progressive Breakdown

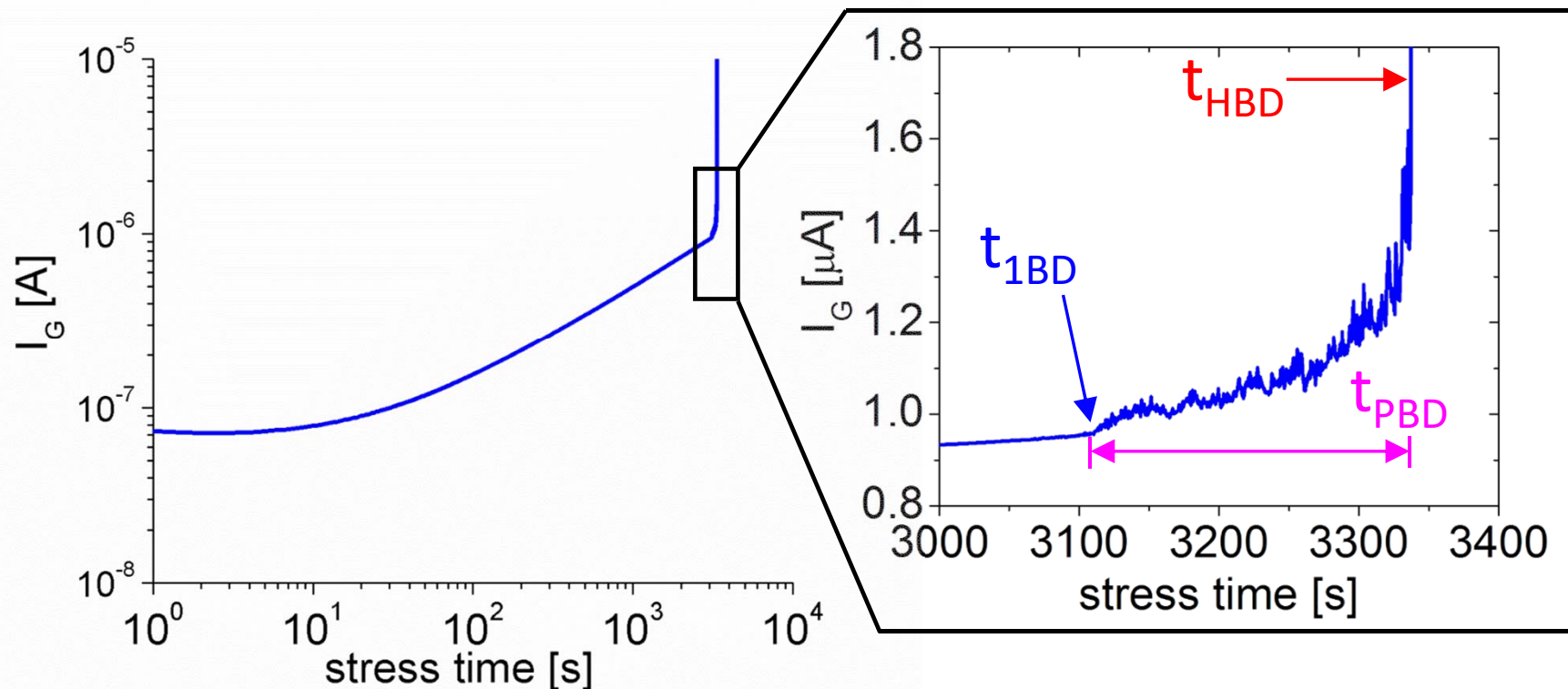
Classic TDDDB experiment: $V_{\text{Gstress}}=12.6 \text{ V}$, $V_{\text{DS}}=0 \text{ V}$



Near breakdown, I_G becomes noisy \rightarrow *progressive breakdown* (PBD)

Observing Progressive Breakdown

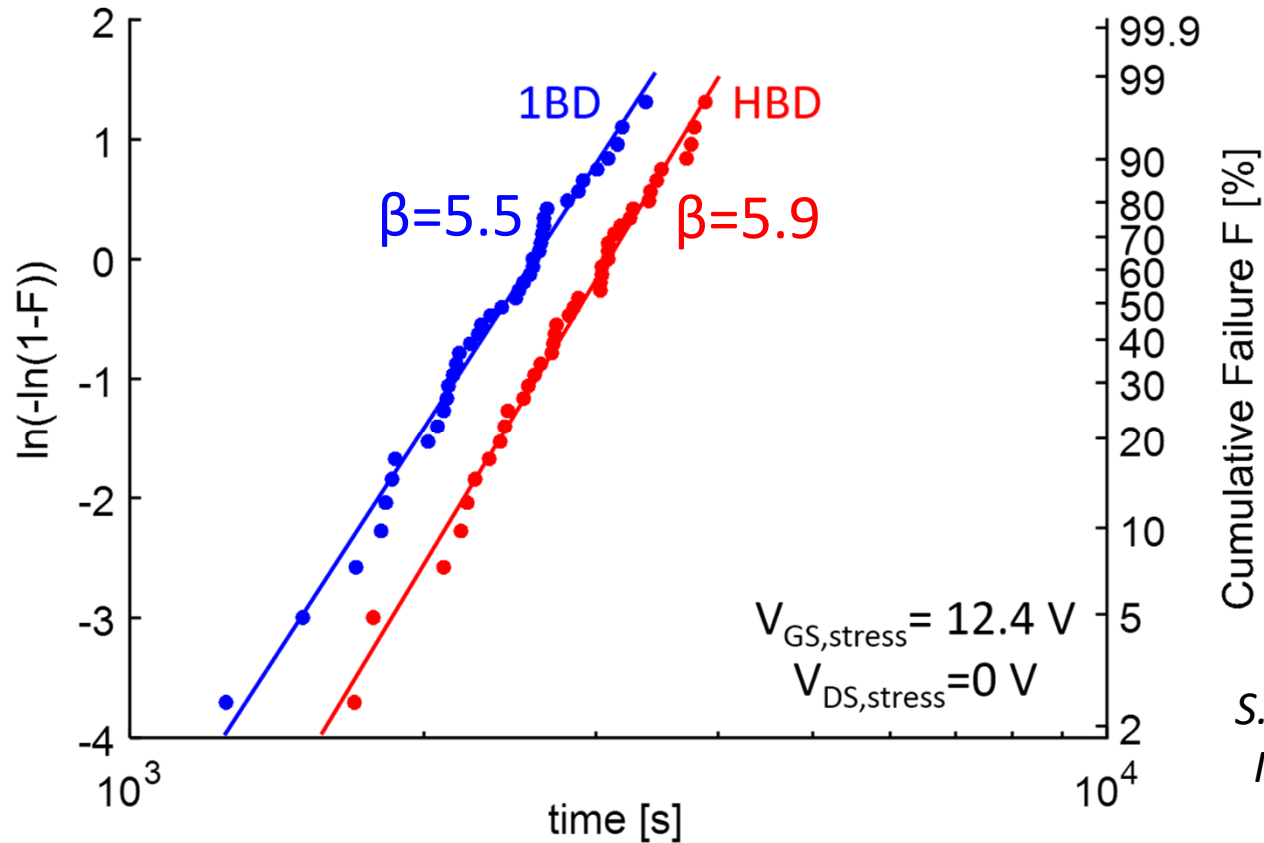
Classic TDDDB experiment: $V_{G\text{stress}}=12.6\text{ V}$, $V_{DS}=0\text{ V}$



- Time-to-first-breakdown t_{1BD} : I_G noise appears
- Hard breakdown (HBD) time t_{HBD} : Jump in I_G , device no longer operational
- t_{PBD} : duration of progressive breakdown (PBD)

GaN Gate Breakdown Statistics

Statistics for time-to-first-breakdown t_{1BD} and hard breakdown t_{HBD}



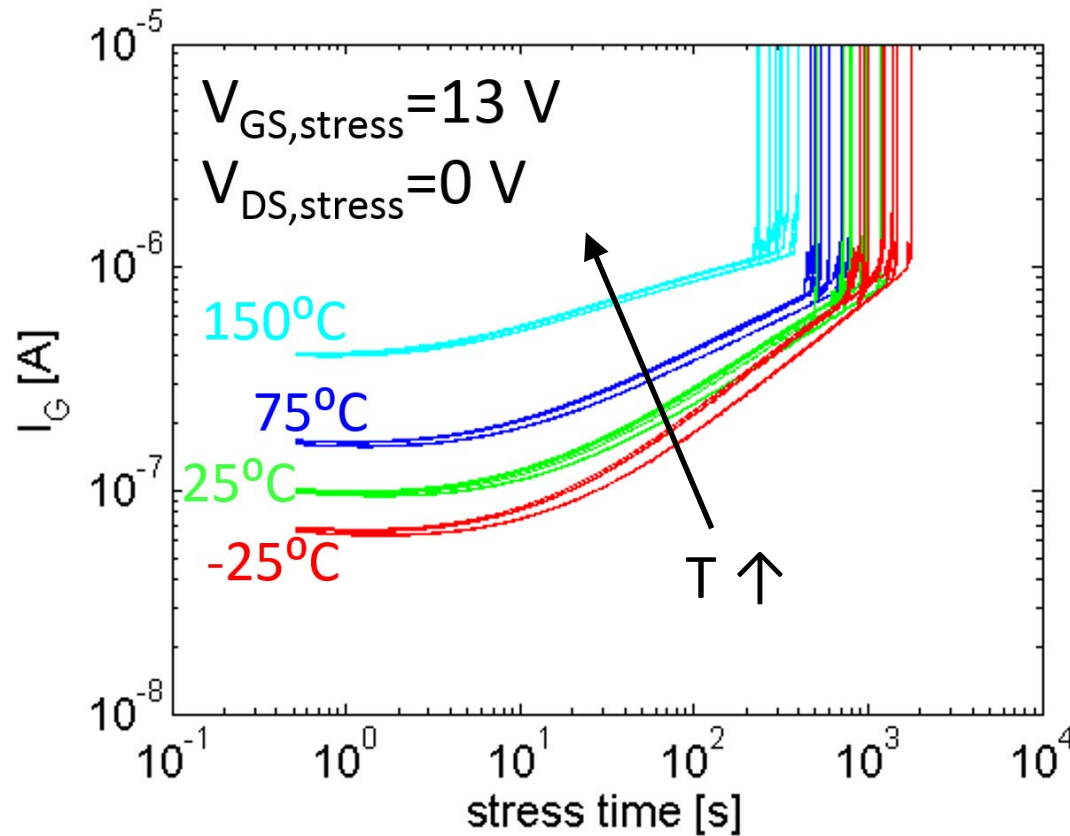
S. Warnock,
IRPS 2016

- Weibull distribution: $\ln[-\ln(1-F)] = \beta \ln(t) - \beta \ln(\eta)$
- Nearly parallel statistics \rightarrow common origin for t_{1BD} and t_{HBD}

Understanding the Role of Temperature

TDDB Across Temperature

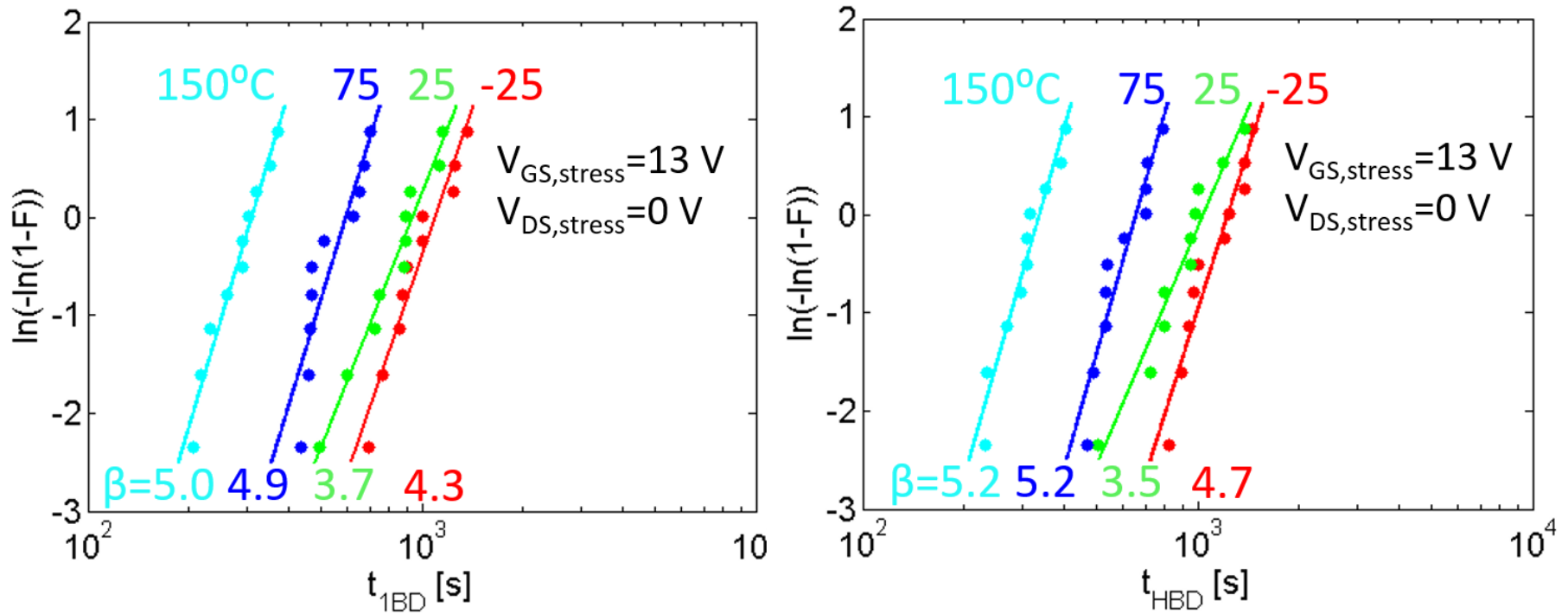
Constant gate-voltage TDDB stress:



- As $T \uparrow$, $I_G \uparrow$
- I_G evolution at each T nearly identical across 10 devices \rightarrow uniform device fabrication

GaN Breakdown Statistics

Weibull plots of time-to-first breakdown t_{1BD} (left) and hard breakdown time t_{HBD} (right)

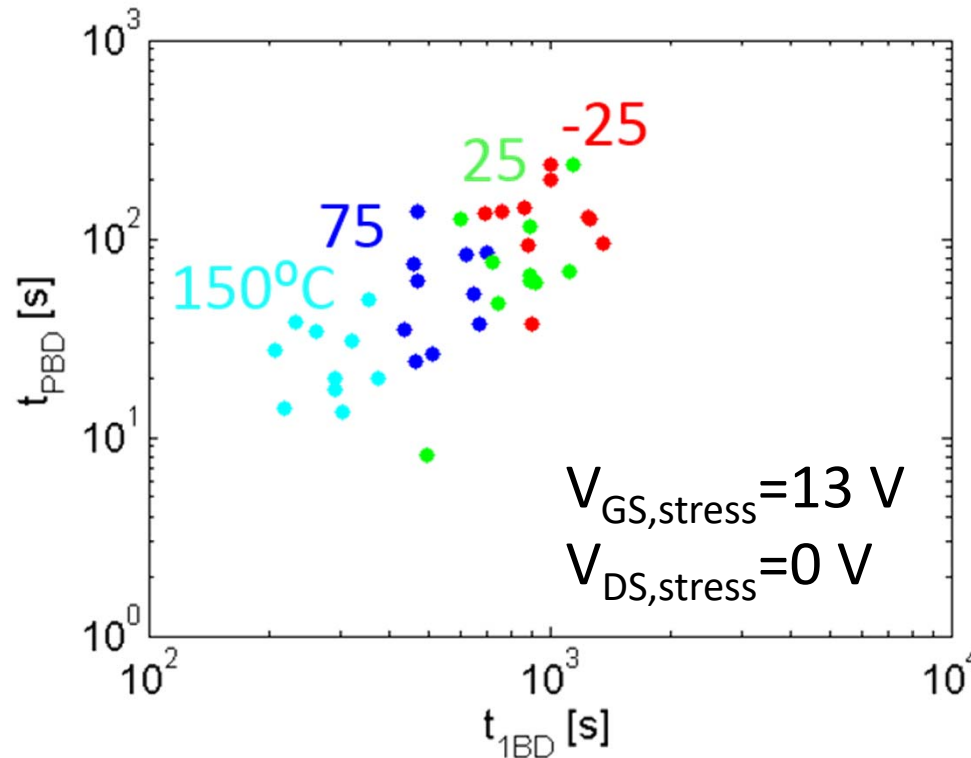


- As $T \uparrow$, t_{HBD} and $t_{1BD} \downarrow$
- Variation in Weibull slopes due to small sample size

GaN Breakdown Statistics

Correlation between time-to-first-breakdown t_{1BD} and PBD duration

t_{PBD}

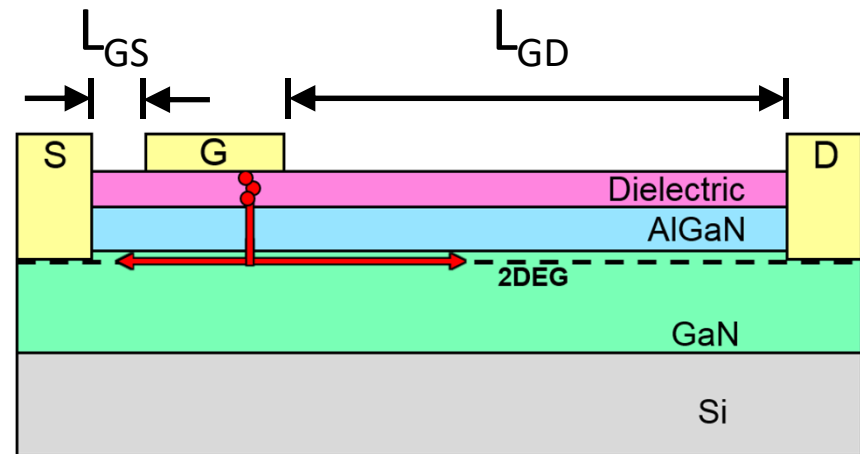
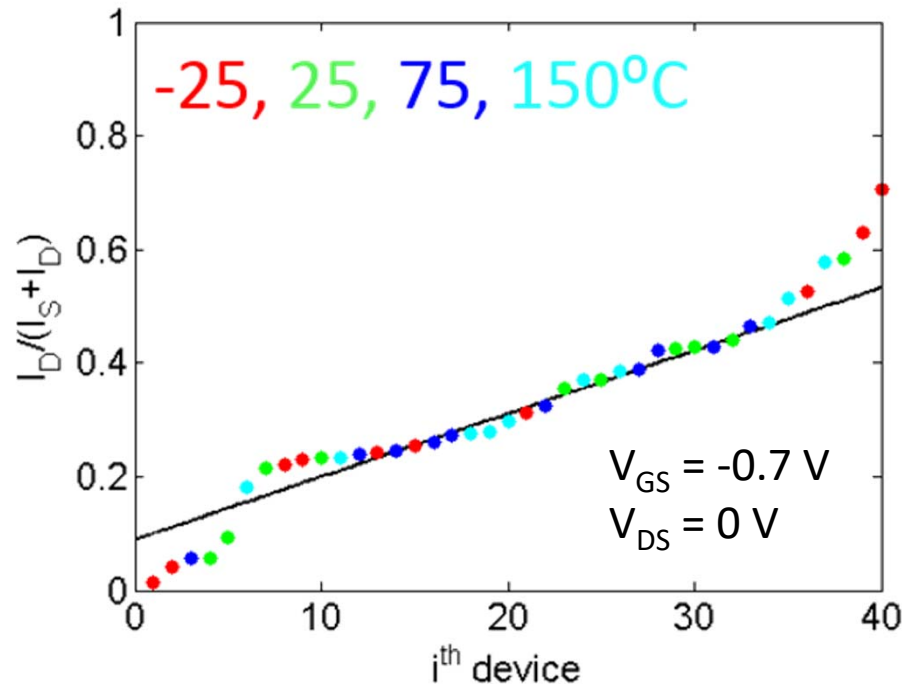


(following E. Wu,
IEDM 2007)

- As $T \downarrow$, t_{PBD} and $t_{1BD} \uparrow$
- t_{1BD} and t_{PBD} independent of one another \rightarrow after first breakdown, defects generated at random until HBD occurs

After Hard Breakdown

Lateral location of BD path: measure $I_D/(I_S+I_D)$ at $V_{DS}=0$ V

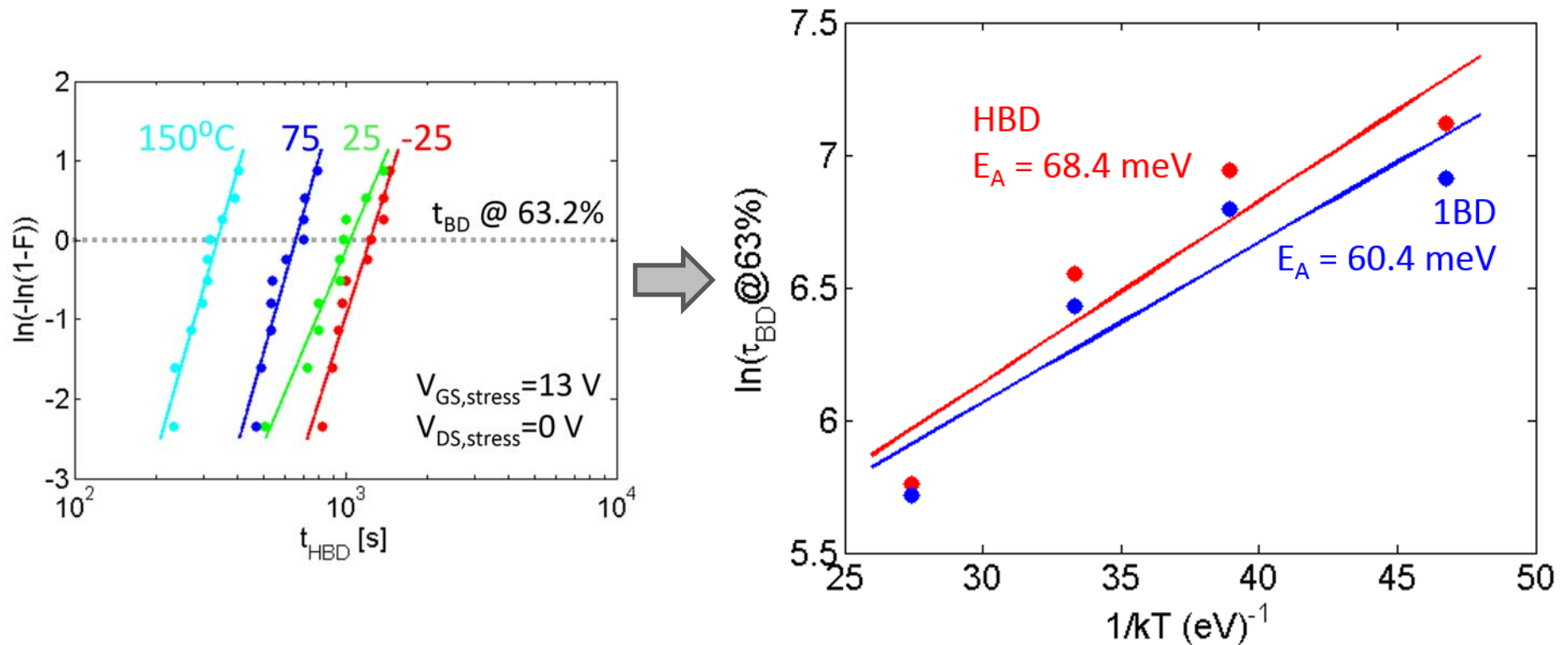


(following R. Degraeve,
IRPS 2001)

- Spread of BD locations across channel, no particular trend with T
- $L_{GD} > L_{GS} \rightarrow$ current preferentially flows through source terminal
- Fit line gives $R_{Daccess} = 5 * R_{Saccess}$

TDDDB Activation Energy

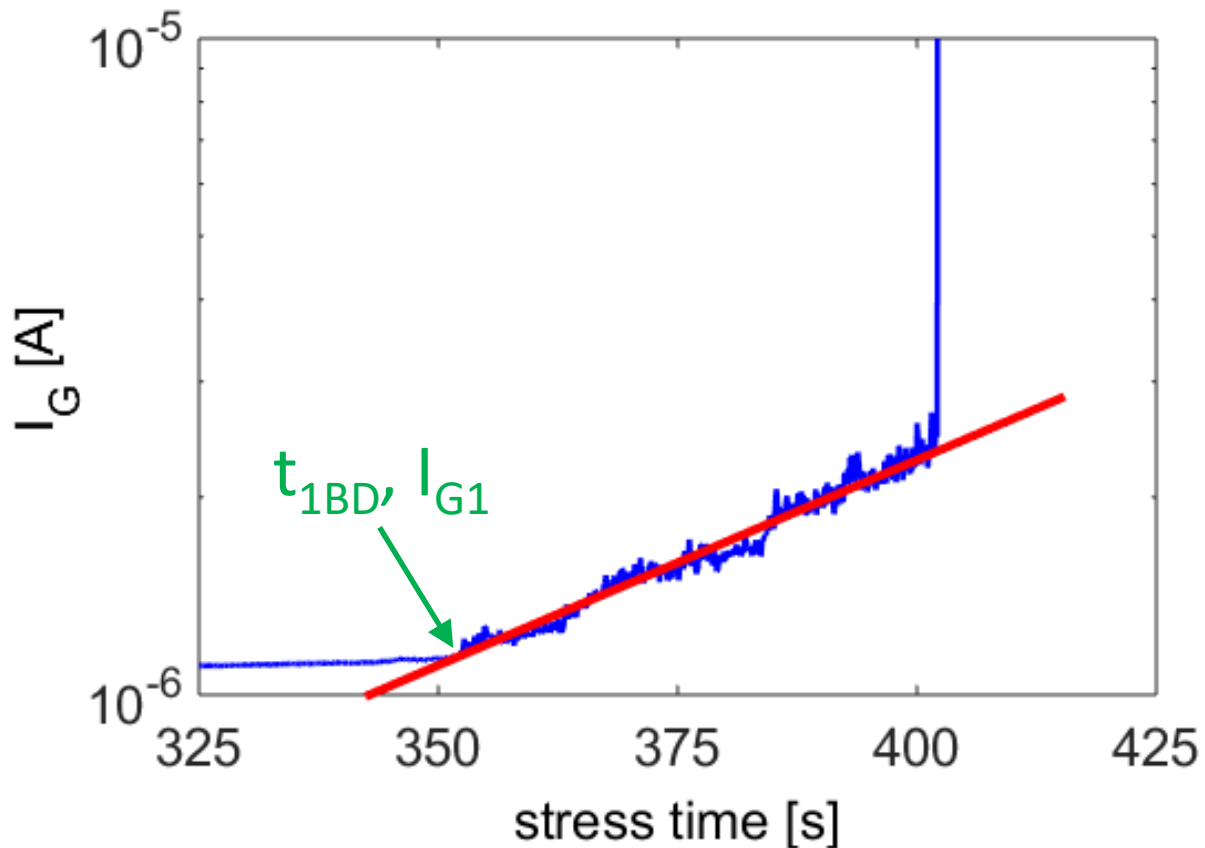
Take the time t_{BD} where Weibull function = 0
(cumulative failure $F=63.2\%$)



- E_A for first breakdown, hard breakdown nearly identical
→ likely common physical origin
- Very small E_A , unlike reports in Si CMOS or other GaN MIS-HEMTs

I_G Evolution During PBD

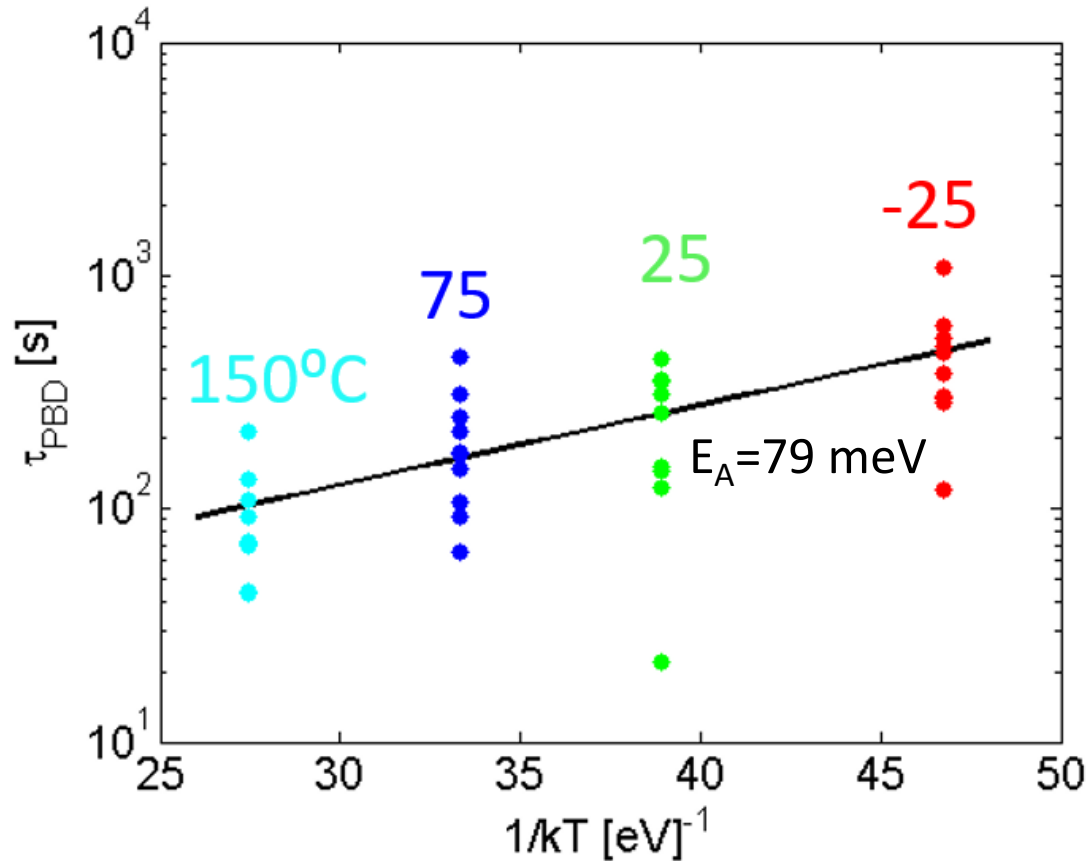
I_G during PBD follows exponential trend, consistent with PBD in Si



Fit with equation of the form $I_{G1} * \exp([t-t_{1BD}]/\tau_{PBD})$

I_G Evolution During PBD

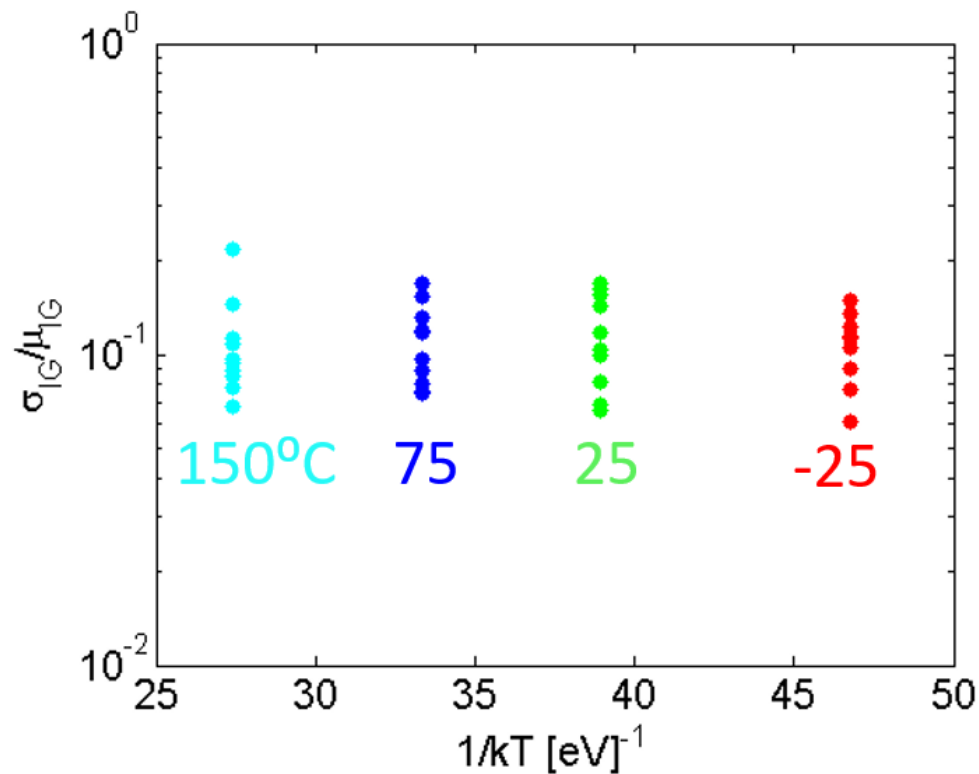
Fit PBD regime with exponential for every measured temperature



- E_A for $\text{avg}(\tau_{PBD}) \sim 79$ meV
- Close to E_A for 1BD, HBD \rightarrow suggests similar underlying mechanism

I_G Noise During PBD

- Does I_G noise increase or decrease with temperature?
- Find standard deviation of I_G and normalize by average I_G (because $I_G \uparrow$ as $T \uparrow$)



No trend over temperature \rightarrow origins of noise likely to be tunneling phenomenon

Conclusions

- Developed methodology to study TDDB and explore PBD in GaN MIS-HEMTs
- Classic t_{1BD} and t_{HBD} statistics
 - Common physical origin for first breakdown and hard breakdown: parallel statistics, similar activation energies
 - However, t_{1BD} not predictive of t_{HBD}
- PBD characteristic time constant, τ_{PBD} , has E_A near that of 1BD, HBD ($\approx 60-80$ meV)
- I_G noise shows no temperature trend, suggests tunneling

Acknowledgements



Questions?